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DT15 RESCRIPTO 14 JAN 2005

# **ARTICLE 34 AMENDMENTS**

AMENDMENT

(amendment under the provision of Article 11)

To : The Commissioner of Patent Office Esq.

5 1. Indication of International Application : PCT/JP03/08989

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4. Object of the Amendment

claims

5. Contents of the Amendment

(1) New claim 9 on page 55 of claims is added.

20 6. List of the Attachments

claims on pages 55

## AMENDMENT

5 a reaction chamber equipped with a substrate heating member capable of loading a substrate, and a shower head capable of spraying a mixed gas uniformly onto a surface of the substrate loaded on the substrate heating member;

an RF power supply connected to the shower head for supplying an RF voltage to the shower head, in respect to the earthed heating member; and

an evacuation apparatus for reducing a pressure in the reaction chamber,

10 wherein the plurality of monomer gas supplying units comprises at least a first monomer supplying unit for vaporizing and supplying a first organosiloxane with cyclosiloxane backbone, and a second monomer supplying unit for vaporizing and supplying a second organosiloxane with straight-chain siloxane backbone.

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8 A vapor deposition apparatus according to claim 7, further comprising a cleaning gas supplying unit,

20 wherein the unit for mixing the plurality of monomer gases mixes a cleaning gas supplied from the cleaning gas supplying unit into the plurality of monomer gases.

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9. (Addition) The organosiloxane copolymer film according to claim 1 for forming the bridge structure by bonding in plural the first organosiloxane and the second organosiloxane via an organic group.